# Monthly LabAdviser update: 15/3 2013

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| Updated Subject  | Contributer | Link to the update pages |
| **Process2Share**Notice this new userwiki where you can share your experience with other users. Use your normal DTU login. | Danchip | <http://process2share.danchip.dtu.dk/index.php/Main_Page> |
| **DRIE Pegasus**The performance of Process A has been investigated as a function of feature size and etch load.  | Jonas M. Lindhard @ danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/DRIE-Pegasus/processA> |
| **New equipment in pipeline and Old equipment for decommissioning**The two pages have been merged into one. | Berit G. Herstrøm @danchip | <http://labadviser.danchip.dtu.dk/index.php/LabAdviser/New_equipment_in_the_pipeline_and_Old_equipment_for_decommissioning#Old_equipment_for_decomisioning> |
| **AOE**Etch load dependency on etching SiO2 with resist mask. | Berit G. Herstrøm @ danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Oxide/SiO2_etch_using_AOE/AOE_SiO2_etch_load_dependency> |
| **Deposition of AlxNy**Added deposition rates. | Katharina Nilson @danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_AlxNy> |
| **Deposition of Copper**Added deposition rates | Katharina Nilson @danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Multisource_PVD/Cu> |
| **Deposition of Aluminium PVD co-sputter/evaporation** Added deposition rates | Katharina Nilson @danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Aluminium/Sputter_rates_for_Al_PVD_co-sputter/evaporation> |
| **LPCVD polySi**SIMS measurement of the boron concentration though a 50 nm polysilicon layer deposited using  the ”polybor” recipe | Azeem Zulfigar @DTU Nanotech | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_polysilicon/Deposition_of_polysilicon_using_LPCVD> |
| **LPCVD nitride in BHF**Added an etch rate of LPCVD nitride in BHF. | Morten B. Mikkelsen @nanotech | [http://labadviser.danchip.dtu.dk/index.php/Specific\_Process\_Knowledge/Etch/Wet\_Silicon\_Oxide\_Etch\_(BHF)#Etch\_rate\_of\_the\_Stoichiometric\_Silicon\_Nitride\_in\_BHF](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Wet_Silicon_Oxide_Etch_%28BHF%29#Etch_rate_of_the_Stoichiometric_Silicon_Nitride_in_BHF)<http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Silicon_Nitride> |
| **Surveys, statistics, monthly LabAdviser update and other info**Have been merged into one page.Notice that you find Danchip responds to remarks given in the surveys. | Danchip | <http://labadviser.danchip.dtu.dk/index.php/Surveys_and_statistics> |
| **Etching Ti**New comparison page | Berit G. Herstrøm @ danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Titanium> |
| **Etching Al**New comparison page | Berit G. Herstrøm @ danchip | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Aluminium> |